



Call for Papers – DPS 2024

45th International Symposium on Dry Process

November 14(Thu) - 15(Fri), 2024

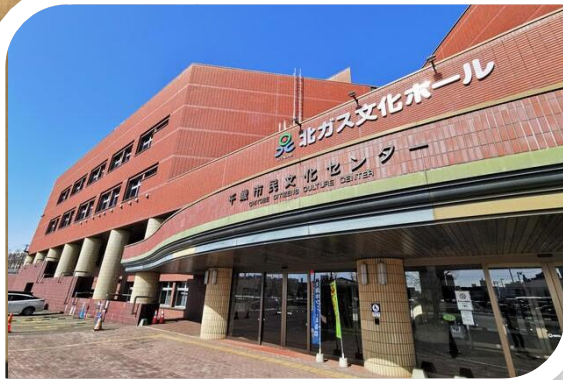
Chitose Civic Culture Center, Hokkaido, Japan



Paper Submission Deadline: July 15, 2024

Author instructions and information about DPS can be found at:

<http://www.dry-process.org/2024/>



The 45th International Symposium on Dry Process (DPS2024) will be held at Chitose Civic Culture Center, Hokkaido, Japan from November 14 to 15, 2024. The Symposium covers all aspects of the rapidly evolving fields of dry processes, including but not limited to plasma etching and deposition processes, diagnostics and modeling of plasmas and surfaces, and surface modifications by plasmas, for the applications in, e.g., microelectronics, power devices, sensors, environmental protection, biological systems, and medicine. The DPS has provided valuable forums for in-depth discussion among professionals and students working in this exciting field for more than four decades.

Theme:

Dry processes and related technologies from fundamentals to applications

Topics:

1. Etching Technologies
2. Manufacturing Technologies (AEC, APC, EES, FDC)
3. Surface Reaction and Damage
4. Plasma Diagnostics and Monitoring Systems
5. Computational Approaches (Modeling, Simulation, Machine Learning, AI, Informatics, DX) for Dry Process
6. Plasma Generation (Equipment/Source)
7. Deposition Technologies (CVD / PVD)
8. Atomic Layer Processes (ALD/ALE)
9. Dry process for Green Transformation:GX (Energy saving technology, Alternative gas, 3D-IC/Packaging)
10. Plasma Processes for New Material Devices (MRAM, Power, Organic, III-V, 2D)
11. Plasma Processes for Biological and Medical application, MEMS
12. Atmospheric Pressure Plasma and Liquid Plasma
13. New Dry Process Concepts

Arranged session:

- AS1 - Understanding the mechanisms for future high-aspect-ratio etching technology
- AS2 - Atomic layer processes (ALE/ALD/ASD) for ultimate control of surface reaction
- AS3 - Breakthrough process technology for advanced logic device fabrication

For further general information, please contact: **e-mail: dps2024@officepolaris.co.jp**

Organizing Committee Chair: Masanobu Honda (TOKYO ELECTRON MIYAGI LTD.)
Executive Committee Chair: Kohki Satoh (Muroran Institute of Technology)
Program Committee Chair: Mitsuhiro Omura (KIOXIA Corp.)
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